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PATENT
Customer Number 22,852
Attorney Docket No. 04329.2072.01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Katsuki OHASHI et al.

Serial No.: 09/870,702

Filed: June 1, 2001

For: METHOD FOR REPAIRING A
PHOTOMASK, METHOD FOR
INSPECTING A PHOTOMASK,
METHOD FOR MANUFACTURING
A PHOTOMASK, AND METHOD
FOR MANUFACTURING A
SEMICONDUCTOR DEVICE

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) Group Art Unit: 1756

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) Examiner: MOHAMEDULLA, Saleha R.
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Assistant Commissioner for Patents
Washington, DC 20231

Sir:

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RESPONSE TO RESTRICTION REQUIREMENT

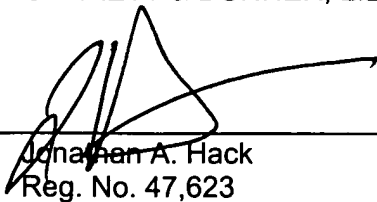
In a restriction requirement dated December 24, 2002, the Examiner required restriction under 35 U.S.C. § 121 between Group I, claims 1-34, 54, and 55, Group III, claims 35-51, and Group IV, claims 52 and 53. (Applicants point out that no Group "II" was designated by the Examiner). Applicants provisionally elect to prosecute Group I, claims 1-34, 54, and 55, characterized by the Examiner as drawn to a method of inspecting and repairing a sample, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By: _____


Jonathan A. Hack
Reg. No. 47,623

Dated: March 21, 2003

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